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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10080424	FILING DATE 02/22/2002	CLASS 438	SUBCLASS 166	GAU 2812	EXAMINER COLEMAN
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**APPLICANTS: Hagino Takashi; Imao Kazuhiro; Wakita Ken; Monzen Toshio; Ogata
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**CONTINUING DATA VERIFIED:

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** FOREIGN APPLICATIONS VERIFIED:
JAPAN 2001-47181 02/22/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

YKI-0084

TITLE : Method for manufacturing polycrystalline semiconductor layers and thin-film transistors, and
laser annealing apparatus

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED

ISSUE FEE

Amount Due Date Paid

☐ TERMINAL
DISCLAIMER

Assistant Examiner

Primary Examiner

PREPARED FOR ISSUE

CLAIMS ALLOWED

Total Claims Print Claim for
O.G.

DRAWING

Sheets Drwg. Figs. Drwg. Print Fig.

Application Examiner

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